



BSI Standards Publication

Semiconductor devices — Micro-electromechanical devices

Part 25: Silicon based MEMS fabrication
technology — Measurement method of
pull-press and shearing strength of micro
bonding area

National foreword

This British Standard is the UK implementation of EN 62047-25:2016. It is identical to IEC 62047-25:2016.

The UK participation in its preparation was entrusted to Technical Committee EPL/47, Semiconductors.

A list of organizations represented on this committee can be obtained on request to its secretary.

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